

FORM PTO-1449 (SUBSTITUTE) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Attorney Docket No.: GR 97 P 1861 Divisional of Applic. No. 09/110,052 Applicant Volker Weinrich et al. Filing Date of Divisional August 24, 2000 Group Art Unit 2815 1746			
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EXAMINER INITIALS	PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
SA ↓	A	4,760,481	07/88	Yuito et al.		
	B	5,057,455	10/91	Foo et al.		
	C	5,122,225	06/92	Douglas		
	D	5,208,170	04/93	Kobeda et al.		
	E	5,341,016	08/94	Prall et al.		
	F	5,350,705	09/94	Brassington et al.		
	G	5,515,984	05/96	Yokoyama et al.		
	H	5,562,801	10/96	Nulty		
	I	5,585,300	12/96	Summerfelt		

FOREIGN PATENT DOCUMENT							
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO	
J	/						
K							
L							
M							
N							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
SA		Patent Abstracts of Japan No. 1-232729 A (Sakota), dated September 18, 1989.
SA		"Etching of TiN local Interconnects Using HBr in a Triode Reactor with Magnetic Confinement" (Zwicker et al.), Proceedings of the International Society for Optical Engineering, Vol. 1803, 1992, pp. 97-106.
EXAMINER		DATE CONSIDERED
Shamim Ahmed		3/14/02

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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EXAMINER INITIALS	A	PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
SA	A	5,621,606	04/97	Hwang			
SA	B	5,717,236	02/98	Shinkawata			
SA	C	5,883,781	03/99	Yamamichi et al.			
	D						
	E						
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		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO	
	J							
	K							
	L							
	M							
	N							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
SA		"Reactive Ion Etching Mechanism of Plasma Enhanced Chemically Vapor Deposited Aluminum Oxide Film in CF ₄ /O ₂ Plasma" (Kim et al.), J. Applied Physics, Vol. 78, No. 3, August 1995, pp. 2045-49.
SA		"Local Plasma Oxidation and Reactive Ion Etching of Metal Films for Ultrafine Line Pattern Inversion and Transfer" (Nulman et al.), J. Vacuum Science Technology, Vol. B1, Oct.-Dec. 1983, pp. 1033-36.

EXAMINER <i>Shamim Ahmed</i>	DATE CONSIDERED <i>3/14/02</i>
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	J						
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	L						
	M						
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)		
SA		"WSi ₂ /Polysilicon Gate Etching Using TiN Hard Mask in Conjunction with Photoresist" (Tabara), J. Applied Physics, Vol. 36, 1997, pp. 2508-13.

EXAMINER <div style="font-family: cursive; font-size: 1.2em;">Shamim Ahmed</div>	DATE CONSIDERED <div style="font-family: cursive; font-size: 1.2em;">3/14/02</div>
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